CMP Conditioner and Pad Characterization!

Len Borucki Araca Incorporated



Conditioner Characterization

Active Diamonds

Active diamonds, or working grit, are defined as those diamonds that modify a pad surface by cutting furrows.



Interferometry of an MMC Mosaic disc with a Teflon coating

PacRim 2005

Active Diamonds

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All diamonds that cut should wear

but

wear by itself is not proof of cutting.

Interferometry of an MMC Mosaic disc with a Teflon coating



PacRim 2005

Furrows are hard to see on commercial pads



... but easy to see on polycarbonate



Conditioner Active Diamond Characterization



Active Diamond Locations on the Conditioner



Active Diamonds on IC-1000



Active Diamond Count vs. Load and Grit Size



Aggressive Diamonds



Characterization of Aggressive Diamonds







Preliminary 24 – hr Wear Results

Non-aggressive Diamond

50 µm

After

Before

Preliminary 24 – hr Wear Results

Aggressive Diamonds Nos. 3 and 4

CMP Pad Characterization

1

Laser Confocal Microscopy

Zeiss LSM 510 Meta NLO

How a Laser Confocal Microscope Works

Topography with Confocal Microscopy

Pad Sample IC-1000

Imaging Conditions

20x objective 488 nm laser 450 gain 27 pinhole 512 x 512 resolution 450 x 450 μm image

10

0

-10

-20

-30

Surface Height (microns)

Interferometry vs Confocal Microscopy

White Light Interferometry ~10-50% valid data Confocal Microscopy 100% valid data

Raw Laser Confocal Topography Images

0.449 x 3.593 mm

IC Less Aggressive Conditioner

IC More Aggressive Conditioner

— Direction of Pad Rotation

Confocal Contact Area Measurements

Confocal Contact Area Images

IC Pad, Less Aggressive Conditioner

Contact Area Shapes

- 10 microns all have a set of a s CATALZASCONSALLANDOSCONTALASCASCASCASCONSO R & O & & Conston

Contact Area Histogram

IC, Less Aggressive Conditioner

Contact Area Histogram

IC, More Aggressive Conditioner

Contact Area Fraction vs. Pressure

IC, Less Aggressive Conditioner

Contact Area Fraction vs. Pressure

IC, More Aggressive Conditioner

Topography-Contact Area Matching

50 μm

Topography-Contact Area Matching

Pad Surface Properties

Navier-Stokes Solution for Flow over Topography

Velocity magnitude, slurry flow over measured pad topography

Navier-Stokes Solution for Flow over Topography

Fluid Pressure

Localized fluid pressures induced by topography may influence the rate

Measured Topography

Contacting Summit.

The topography is the same as the previous slide except it is depicted using a color contour map rather than a relief map.

Close-up of Region in Contact

X (m)

